

EE C245 - ME C218

Introduction to MEMS Design


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Lecture Module 9: Energy Methods

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Lecture Outline

- Reading: Senturia, Chpt. 10
- Lecture Topics:
 - ↳ Energy Methods
 - Virtual Work
 - Energy Formulations
 - Tapered Beam Example
 - Estimating Resonance Frequency

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Energy Methods

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More General Geometries

- Euler-Bernoulli beam theory works well for simple geometries
- But how can we handle more complicated ones?
- Example: tapered cantilever beam
- Objective: Find an expression for displacement as a function of location x under a point load F applied at the tip of the free end of a cantilever with tapered width $W(x)$

Top view of cantilever's $W(x)$

$W(x) = W(1 - \frac{x}{2L_c})$

50% taper


$x = L_c$

F

x

y

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Solution: Use Principle of Virtual Work

- In an energy-conserving system (i.e., elastic materials), the energy stored in a body due to the quasi-static (i.e., slow) action of surface and body forces is equal to the work done by these forces ...
- Implication: if we can formulate **stored energy** as a function of the deformation of a mechanical object, then we can determine how an object responds to a force by determining the shape the object must take in order to **minimize** the **difference U** between the stored energy and the work done by the forces:

$$U = \text{Stored Energy} - \text{Work Done}$$

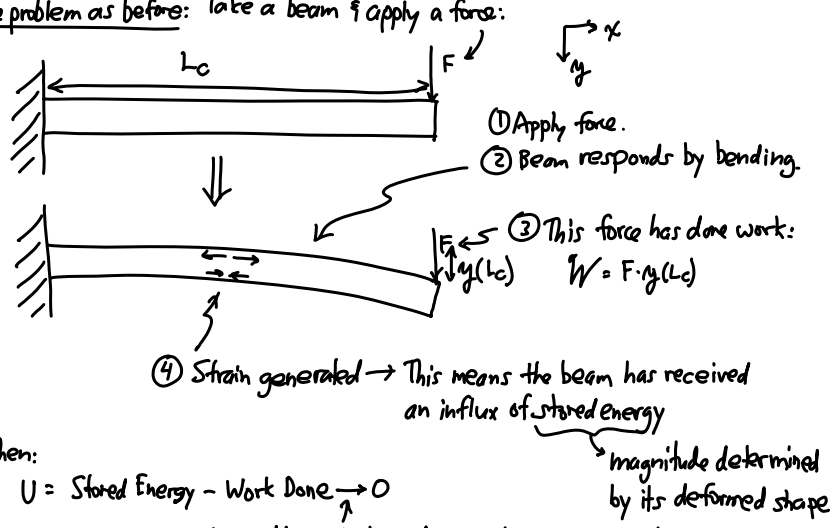
- Key idea: we don't have to reach $U = 0$ to produce a very useful, approximate *analytical* result for load-deflection

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More Visual Description ...

Same problem as before: Take a beam & apply a force:



① Apply force.

② Beam responds by bending.

③ This force has done work:
 $W = F \cdot y(L_c)$

④ Strain generated \rightarrow This means the beam has received an influx of stored energy

⑤ Then:
 $U = \text{Stored Energy} - \text{Work Done} \rightarrow 0$
 When we choose the right shape! (This is how we get the beam's response to F !)

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Fundamentals: Energy Density

- Strain energy density: [J/m³] $W(Q) = \int_0^Q \frac{Q}{C} dQ \rightarrow$ charging a capacitor from 0 \rightarrow Q takes this much work
 \rightarrow stored energy on a capacitor
 \rightarrow To find work done in straining material

This is a definition, so really can just say it's a definition.

$$w = \int_0^{\epsilon_x} \sigma_x d\epsilon_x \quad \text{x-axis normal stress term}$$

$\sigma_x(\epsilon_x) \rightarrow$ relates stress to strain @ position (x, y, z)
 $(\sigma_x = E\epsilon_x) \Rightarrow w = \int_0^{\epsilon_x} E\epsilon_x d\epsilon_x = \frac{1}{2} E\epsilon_x^2$

$W(q) = \int_0^q e(q) dq$ $q = \text{displacement}$ $e = \text{effort}$ } Generic Definition of Work

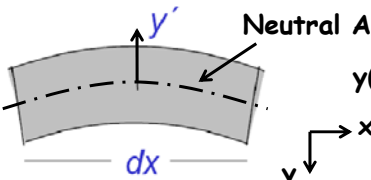
- Total strain energy [J]:
 \rightarrow Integrate over all strains (normal and shear)

$$W = \iiint \left(\frac{1}{2} E(\epsilon_x^2 + \epsilon_y^2 + \epsilon_z^2) + \frac{1}{2} G(\gamma_{xy}^2 + \gamma_{xz}^2 + \gamma_{yz}^2) \right) dV$$

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Bending Energy Density



Neutral Axis
 $y(x) = \text{transverse displacement of neutral axis}$

- First, find the bending energy dW_{bend} in an infinitesimal length dx : $W = \text{width}$


$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \epsilon_x^2(y') dy'$$

$$\left[\frac{1}{R} = \frac{d^2 y}{dx^2}, \epsilon_x = \frac{y'}{R} \right] \Rightarrow \epsilon_x(y) = y' \frac{d^2 y}{dx^2}$$

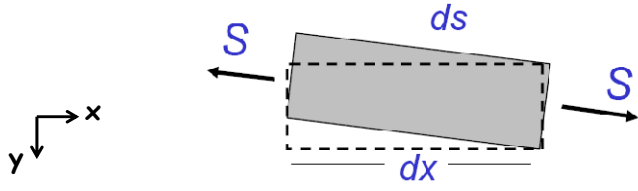
$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \left(y' \frac{d^2 y}{dx^2} \right)^2 dy' = \frac{1}{2} E \left(\frac{Wh^3}{12} \right) \left(\frac{d^2 y}{dx^2} \right)^2 dx$$

$$\therefore W_{\text{bend}} = \frac{1}{2} E I_z \int_0^L \left(\frac{d^2 y}{dx^2} \right)^2 dx$$

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Energy Due to Axial Load




- Strain due to axial load S contributes an energy dW_{stretch} in length dx , since lengthening of the different element dx (to ds) results in a strain ϵ_x

$ds = [(dx)^2 + (dy)^2]^{1/2} = dx \left[1 + \left(\frac{dy}{dx} \right)^2 \right]^{1/2} \xrightarrow{\text{Binomial Theorem}} dx \left[1 + \frac{1}{2} \left(\frac{dy}{dx} \right)^2 \right]$

$\therefore \epsilon_x = \frac{ds - dx}{dx} = \frac{1}{2} \left(\frac{dy}{dx} \right)^2$

$\left[dW_{\text{axial}} = S \epsilon_x dx = \frac{1}{2} S \left(\frac{dy}{dx} \right)^2 dx \right] \Rightarrow \boxed{W_{\text{axial}} = \frac{1}{2} S \int_0^L \left(\frac{dy}{dx} \right)^2 dx}$
 \nwarrow Axial Strain Energy

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Shear Strain Energy

$$W_{\text{shear}} = \frac{3(EI_z)^2}{4GWh} \int_0^L \left(\frac{d^3 y}{dx^3} \right)^2 dx$$

\nearrow Shear Modulus

- See W.C. Albert, "Vibrating Quartz Crystal Beam Accelerometer," Proc. ISA Int. Instrumentation Symp., May 1982, pp. 33-44

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 **Applying the Principle of Virtual Work**


- **Basic Procedure:**
 - ↳ Guess the form of the beam deflection under the applied loads
 - ↳ Vary the parameters in the beam deflection function in order to minimize:

$$U = \underbrace{\sum_j W_j}_{\text{Sum strain energies}} - \sum_i F_i u_i$$

Assumes point load

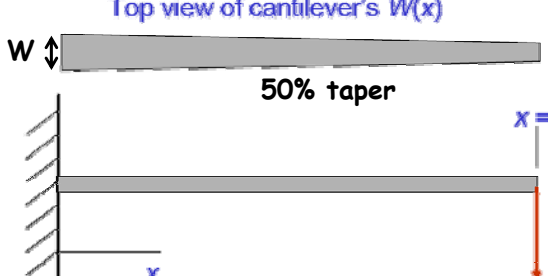
Displacement at point load
- ↳ Find minima by simply setting derivatives to zero
- See Senturia, pg. 244, for a general expression with distributed surface loads and body forces

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 **Example: Tapered Cantilever Beam**

- **Objective:** Find an expression for displacement as a function of location x under a point load F applied at the tip of the free end of a cantilever with tapered width $W(x)$

Top view of cantilever's $W(x)$




$W(x) = W(1 - \frac{x}{2L_c})$

Adjustable parameters: minimize U

$y(x) = c_2 x^2 + c_3 x^3$

- Start by guessing the solution
 - ↳ It should satisfy the boundary conditions
 - ↳ The strain energy integrals shouldn't be too tedious
 - This might not matter much these days, though, since one could just use matlab or mathematica

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Strain Energy And Work By F

$U = \mathcal{W}_{bend} - F \cdot y(L_c)$

$\mathcal{W}_{bend} = \frac{1}{2} E \int_0^{L_c} I_z(x) \left(\frac{d^2 y}{dx^2} \right)^2 dx \quad \text{(Bending Energy)}$

$I_z(x) = \frac{W(x)h^3}{12}$


$W(x) = W \left(1 - \frac{x}{2L_c} \right)$

$\frac{d^2 y}{dx^2} = 2c_2 + 6c_3 x \quad \text{(Using our guess)}$

Tip Deflection

$= \frac{1}{24} E W h^3 \int_0^{L_c} \left(1 - \frac{x}{2L_c} \right) (2c_2 + 6c_3 x)^2 dx - F(c_2 L_c^2 + c_3 L_c^3)$

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Find c_2 and c_3 That Minimize U


- Minimize $U \rightarrow$ basically, find the c_2 and c_3 that brings U closest to zero (which is what it would be if we had guessed correctly)
- The c_2 and c_3 that minimize U are the ones for which the partial derivatives of U with respect to them are zero:

$$\frac{\partial U}{\partial c_2} = 0 \qquad \frac{\partial U}{\partial c_3} = 0$$

- Proceed:
 - ↳ First, evaluate the integral to get an expression for U :

$$U = E W h^3 \left\{ \frac{5c_3^2}{16} L_c^3 + \frac{c_2 c_3}{3} L_c^2 + \frac{c_2^2}{8} L_c \right\} - F(c_2 L_c^2 + c_3 L_c^3)$$

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Minimize U (cont)


- Evaluate the derivatives and set to zero:

$$\frac{\partial U}{\partial c_2} = 0 = \left(\frac{EWh^3}{3} c_3 - F \right) L_c^2 + \left(\frac{EWh^3}{4} c_2 \right) L_c$$

$$\frac{\partial U}{\partial c_3} = 0 = \left(\frac{5}{8} EWh^3 c_3 - F \right) L_c^3 + \left(\frac{EWh^3}{3} c_2 \right) L_c^2$$
- Solve the simultaneous equations to get c_2 and c_3 :

$$c_2 = \begin{pmatrix} 84 \\ 13 \end{pmatrix} \frac{FL_c}{EWh^3} \quad c_3 = -\begin{pmatrix} 24 \\ 13 \end{pmatrix} \frac{F}{EWh^3}$$

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The Virtual Work-Derived Solution


- And the solution:

$$y(x) = \left(\frac{24F}{13EWh^3} \right) \left(\left(\frac{7}{2} \right) L_c - x \right) x^2$$
- Solve for tip deflection and obtain the spring constant:

$$y(L_c) = \left(\frac{24F}{13EWh^3} \right) \left(\frac{5}{2} \right) L_c^3 \quad k_c = F / y(L_c) = \left(\frac{13EWh^3}{60L_c^3} \right)$$
- Compare with previous solution for constant-width cantilever beam (using Euler theory):

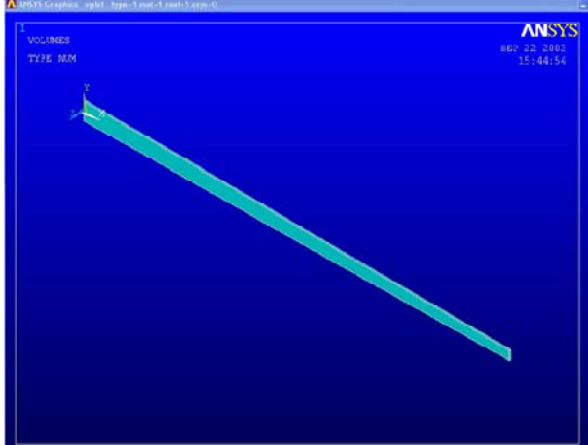
$$y(L_c) = \left(\frac{4F}{EWh^3} \right) L_c^3 \longrightarrow \text{13\% smaller than tapered-width case}$$

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Comparison With Finite Element Simulation

- Below: ANSYS finite element model with
 - $L = 500 \mu\text{m}$ $W_{\text{base}} = 20 \mu\text{m}$ $E = 170 \text{ GPa}$
 - $h = 2 \mu\text{m}$ $W_{\text{tip}} = 10 \mu\text{m}$



- Result:** (from static analysis)
 - $k = 0.471 \mu\text{N/m}$
- This matches the result from energy minimization to 3 significant figures

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Need a Better Approximation?

- Add more terms to the polynomial
- Add other strain energy terms:
 - Shear: more significant as the beam gets shorter
 - Axial: more significant as deflections become larger
- Both of the above remedies make the math more complex, so encourage the use of math software, such as Mathematica, Matlab, or Maple
- Finite element analysis is really just energy minimization
- If this is the case, then why ever use energy minimization analytically (i.e., by hand)?
 - Analytical expressions, even approximate ones, give insight into parameter dependencies that FEA cannot
 - Can compare the importance of different terms
 - Should use in tandem with FEA for design

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Estimating Resonance Frequency

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Clamped-Clamped Beam μ Resonator

Resonator Beam
 W_r , L_r , h

Electrode
 v_i

Sinusoidal Excitation
 $v_i = V_i \cos[\omega_o t] \rightarrow f_i = F_i \cos[\omega_o t]$

Voltage-to-Force Capacitive Transducer
 V_P


Sinusoidal Forcing Function
 i_o

$Q \sim 10,000$

ω_0 , ω

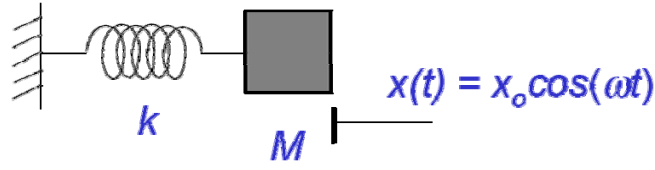
- $\omega \neq \omega_0$: small amplitude
- $\omega = \omega_0$: maximum amplitude \rightarrow beam reaches its maximum potential and kinetic energies

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Estimating Resonance Frequency

- Assume simple harmonic motion:




- Potential Energy:

$$W(t) = \frac{1}{2} k x^2(t) = \frac{1}{2} k x_o^2 \cos^2(\omega t)$$

- Kinetic Energy:

$$K(t) = \frac{1}{2} M \dot{x}^2(t) = \frac{1}{2} M x_o^2 \omega^2 \sin^2(\omega t)$$

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Estimating Resonance Frequency (cont)

- Energy must be conserved:
 - Potential Energy + Kinetic Energy = Total Energy
 - Must be true at every point on the mechanical structure

Occurs at peak displacement

Maximum Potential Energy

$W_{\max} = \frac{1}{2} k x_o^2$

Stiffness

Displacement Amplitude

Occurs when the beam moves through zero displacement

Maximum Kinetic Energy

$K_{\max} = \frac{1}{2} M \omega^2 x_o^2$

Mass

Radian Frequency

$W_{\max} = \frac{1}{2} k x_o^2 = K_{\max} = \frac{1}{2} M \omega^2 x_o^2$

- Solving, we obtain for resonance frequency:

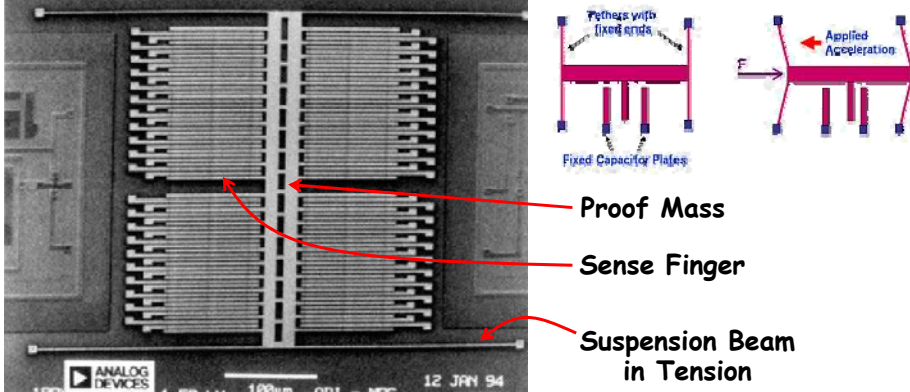
$$\omega = \sqrt{\frac{k}{M}}$$

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Example: ADXL-50

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- The proof mass of the ADXL-50 is many times larger than the effective mass of its suspension beams
 - Can ignore the mass of the suspension beams (which greatly simplifies the analysis)
- Suspension Beam: $L = 260 \mu\text{m}$, $h = 2.3 \mu\text{m}$, $W = 2 \mu\text{m}$

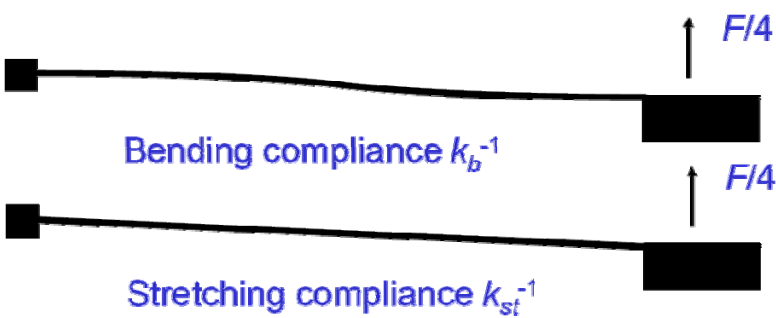


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Lumped Spring-Mass Approximation

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- Mass is dominated by the proof mass
 - 60% of mass from sense fingers
 - Mass = $M = 162 \text{ ng}$ (nano-grams)
- Suspension: four tensioned beams
 - Include both bending and stretching terms [A.P. Pisano, BSAC Inertial Sensor Short Courses, 1995-1998]



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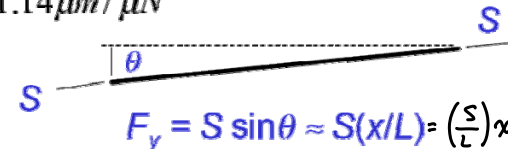


ADXL-50 Suspension Model

- Bending contribution:

$$k_b^{-1} = (1/k_c + 1/k_e) = 2 \left[\frac{(L/2)^3}{3E(Wh^3/12)} \right] = \frac{L^3}{EWh^3} = 4.2 \mu\text{m} / \mu\text{N}$$
- Stretching contribution:


$$k_{st}^{-1} = L/S = \frac{L}{\sigma_r Wh} = 1.14 \mu\text{m} / \mu\text{N}$$



$F_y = S \sin \theta \approx S(x/L) = \underbrace{\left(\frac{S}{L}\right)}_{k_{st}} x$
- Total spring constant: *add bending to stretching*
(since they are in parallel)

$$k = 4(k_b + k_{st}) = 4(0.24 + 0.88) = 4.5 \mu\text{N} / \mu\text{m}$$

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ADXL-50 Resonance Frequency

- Using a lumped mass-spring approximation:

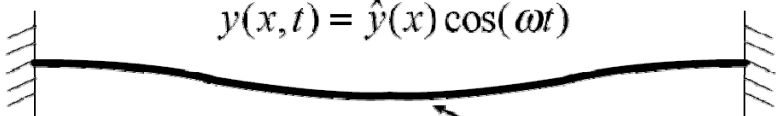
$$f = \frac{1}{2\pi} \sqrt{\frac{k}{M}} = \frac{1}{2\pi} \sqrt{\frac{4.48 \text{ N/m}}{162 \times 10^{-12} \text{ kg}}} = 26.5 \text{ kHz}$$
- On the ADXL-50 Data Sheet: $f_0 = 24 \text{ kHz}$
 - ↗ Why the 10% difference?
 - ↗ Well, it's approximate ... plus ...
 - ↗ Above analysis does not include the frequency-pulling effect of the DC bias voltage across the plate sense fingers and stationary sense fingers ... something we'll cover later on ...

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Distributed Mechanical Structures

- Vibrating structure displacement function:

$$y(x, t) = \hat{y}(x) \cos(\omega t)$$



Maximum displacement function
(i.e., mode shape function)
Seen when velocity $\dot{y}(x, t) = 0$
- Procedure for determining resonance frequency:
 - ↗ Use the static displacement of the structure as a trial function and find the strain energy \mathcal{W}_{\max} at the point of maximum displacement (e.g., when $t=0, \pi/\omega, \dots$)
 - ↗ Determine the maximum kinetic energy when the beam is at zero displacement (e.g., when it experiences its maximum velocity)
 - ↗ Equate energies and solve for frequency

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Maximum Kinetic Energy

- Displacement: $y(x, t) = \hat{y}(x) \cos[\omega t]$
- Velocity: $v(x, t) = \frac{\partial y(x, t)}{\partial t} = -\omega \hat{y}(x) \sin[\omega t]$
- At times $t = \pi/(2\omega), 3\pi/(2\omega), \dots$


$$y(x, t) = 0$$


Velocity topographical mapping

- ↗ The displacement of the structure is $y(x, t) = 0$
- ↗ The velocity is maximum and all of the energy in the structure is kinetic (since $\mathcal{W}=0$):

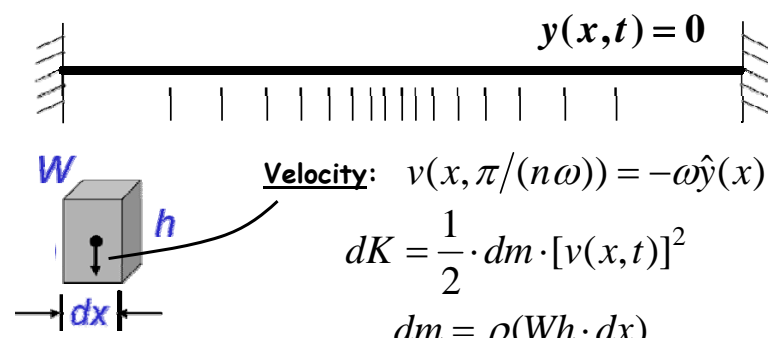
$$v(x, \pi/(n\omega)) = -\omega \hat{y}(x)$$

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Maximum Kinetic Energy (cont)

- At times $t = \pi/(2\omega), 3\pi/(2\omega), \dots$



Velocity: $v(x, \pi/(n\omega)) = -\omega \hat{y}(x)$


$$dK = \frac{1}{2} \cdot dm \cdot [v(x, t)]^2$$

$$dm = \rho(Wh \cdot dx)$$

- Maximum kinetic energy:

$$K_{\max} = \int_0^L \frac{1}{2} \rho Wh dx v^2(x, t') = \int_0^L \frac{1}{2} \rho Wh \omega^2 \hat{y}^2(x) dx$$

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The Raleigh-Ritz Method

- Equate the maximum potential and maximum kinetic energies:

$$K_{\max} = \int_0^L \frac{1}{2} \rho Wh \omega^2 \hat{y}^2(x) dx = \mathcal{W}_{\max}$$

- Rearranging yields for resonance frequency:

$$\omega = \sqrt{\frac{\mathcal{W}_{\max}}{\int_0^L \frac{1}{2} \rho Wh \hat{y}^2(x) dx}}$$

ω = resonance frequency

\mathcal{W}_{\max} = maximum potential energy

ρ = density of the structural material

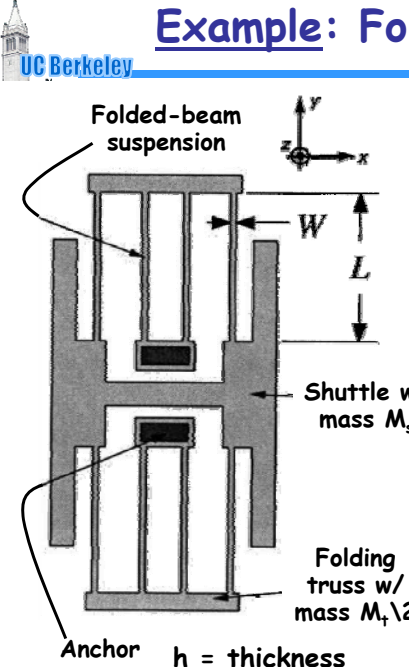
W = beam width

h = beam thickness

$\hat{y}(x)$ = resonance mode shape

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Example: Folded-Beam Resonator



• Derive an expression for the resonance frequency of the folded-beam structure at left.

Use Rayleigh-Ritz method.

$$KE_{max} = PE_{max}$$

Kinetic Energy:

$$KE_{max} = \underbrace{KE_s}_{\text{shuttle}} + \underbrace{KE_t}_{\text{truss}} + \underbrace{KE_b}_{\text{beams}}$$

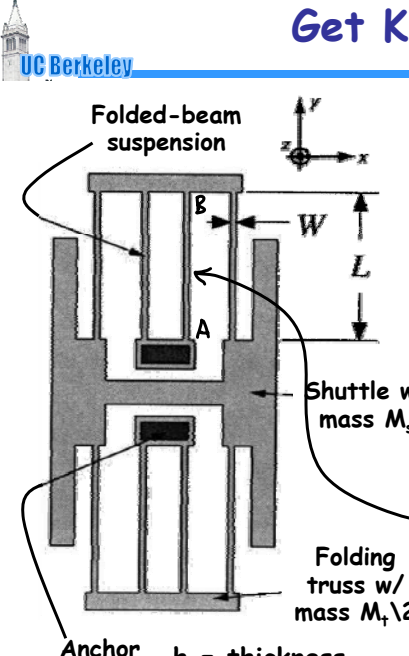
$$= \frac{1}{2} N_s^2 M_s + \frac{1}{2} N_t^2 M_t + \frac{1}{2} \int N_b^2 dM_b$$

mass of both trusses

Must integrate since the beam velocity is a function of location y !

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Get Kinetic Energies



Velocity of the shuttle: $N_s = \omega_0 X_0$

Resonance Freq. Maximum Displacement Amplitude

$$\therefore KE_s = \frac{1}{2} N_s^2 M_s = \frac{1}{2} \omega_0^2 X_0^2 M_s$$

Velocity of the truss: $N_t = \frac{1}{2} N_s = \frac{1}{2} \omega_0 X_0$

$$\therefore KE_t = \frac{1}{2} \left(\frac{1}{2} \omega_0 X_0 \right)^2 M_t = \frac{1}{8} \omega_0^2 X_0^2 M_t$$


Velocity of the beam segments:

⇒ assume the mode shape is the same as the static displacement shape

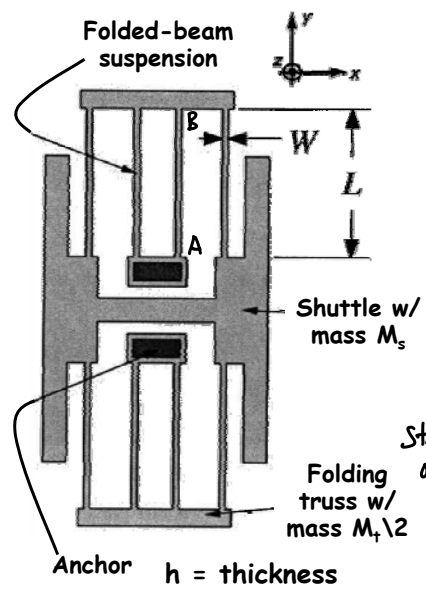
⇒ For segment AB:

$$\delta(y) = \frac{F_x}{48 E I_z} (3Ly^2 - 2y^3) \quad 0 \leq y \leq L \quad (1)$$

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Get Kinetic Energies (cont)



Folded-beam suspension

Shuttle w/ mass M_s

Folding truss w/ mass $M_t/2$

Anchor $h = \text{thickness}$

At $y=L$: $x(L) = \frac{X_0}{2} = \frac{F_x L^3}{48 E I_z}$

Substituting into (1):

$$\hat{x}(y) = \frac{X_0}{2} \left[3 \left(\frac{y}{L} \right)^2 - 2 \left(\frac{y}{L} \right)^3 \right]$$

Which yields for velocity:

$$v_b(y)|_{[AB]} = \frac{X_0}{2} \left[3 \left(\frac{y}{L} \right)^2 - 2 \left(\frac{y}{L} \right)^3 \right] \omega_0$$

Plugging into the expression for KE_b :


$$KE_{[AB]} = \frac{1}{2} \int_0^L \frac{X_0^2 \omega_0^2}{4} \left[3 \left(\frac{y}{L} \right)^2 - 2 \left(\frac{y}{L} \right)^3 \right]^2 dM_{[AB]}$$

Static mass of beam [AB]

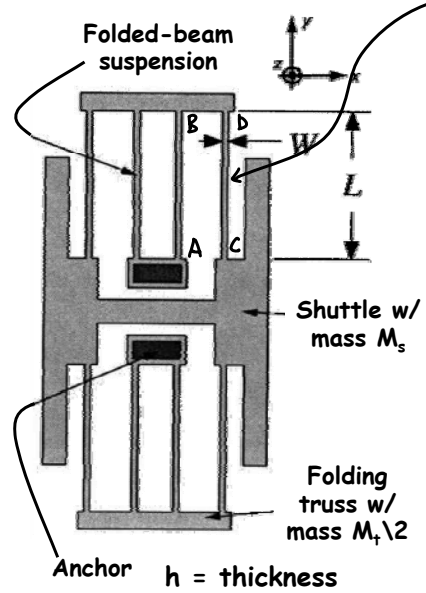
$$= \frac{X_0^2 \omega_0^2 M_{[AB]}}{8L} \int_0^L \left[3 \left(\frac{y}{L} \right)^2 - 2 \left(\frac{y}{L} \right)^3 \right]^2 dy$$

$KE_{[AB]} = \frac{13}{280} X_0^2 \omega_0^2 M_{[AB]}$

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Get Kinetic Energies (cont)



Folded-beam suspension

Shuttle w/ mass M_s

Folding truss w/ mass $M_t/2$

Anchor $h = \text{thickness}$

For segment CD:

$$v_b(y)|_{[CD]} = X_0 \left[1 - \frac{3}{2} \left(\frac{y}{L} \right)^2 + \left(\frac{y}{L} \right)^3 \right] \omega_0$$

Thus:

$$KE_{[CD]} = \frac{X_0^2 \omega_0^2 M_{[CD]}}{2L} \int_0^L \left[1 - \frac{3}{2} \left(\frac{y}{L} \right)^2 + \left(\frac{y}{L} \right)^3 \right]^2 dy$$

$KE_{[CD]} = \frac{83}{280} X_0^2 \omega_0^2 M_{[CD]}$ Static mass of beam [CD]

Let $M_b \triangleq$ total mass of the 8 beams.

Then: $M_{[AB]} = M_{[CD]} = \frac{1}{8} M_b$


Thus:

$$KE_b = 4 KE_{[AB]} + 4 KE_{[CD]} = \frac{6}{35} X_0^2 \omega_0^2 M_b$$

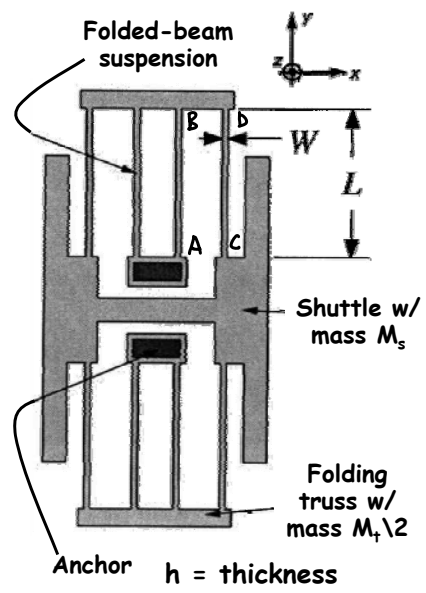
and

$KE_{max} = X_0^2 \omega_0^2 \left[\frac{1}{2} M_s + \frac{1}{8} M_t + \frac{6}{35} M_b \right]$

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Get Potential Energy & Frequency



Anchor $h = \text{thickness}$

PE_{max} is simply the work done to achieve maximum deflection:

$$PE_{max} = \frac{1}{2} k_x X_0^2 \quad \leftarrow = k_c$$

Thus, using Rayleigh-Ritz:

$$KE_{max} = PE_{max}$$

$$\cancel{X_0}^2 \omega_0^2 \left[\frac{1}{2} M_s + \frac{1}{8} M_t + \frac{6}{35} M_b \right] = \frac{1}{2} k_x \cancel{X_0}^2 \quad \leftarrow = k_c$$

$$\omega_0 = \left[\frac{k_x}{M_{eq}} \right]^{1/2} \quad \leftarrow = k_c$$

Where $M_{eq} = M_s + \frac{1}{4} M_t + \frac{12}{35} M_b$

(Resonance Frequency of a Folded-Beam Suspended Shuttle)

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